SiPM: almost an Ideal Low Light Level Sensor for CTA SST

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What LLL sensor can we dream about ?

- Nearly 100 % QE and photon detection efficiency (PDE)
- Could be made in very large and in very small sizes
- Few ps fast (in air and in many materials the light speed is usually 20-30 cm/ns; in 5 ps it will make 1-1.5 mm)
- Signal amplification x10⁶
- Noiseless amplification: F-factor 1.001
- Few % amplitude resolution
- No fatigue, no degradation in lifetime
- Low power consumption
- Operation at ambient temperatures
- No danger to expose to light
- Insensitive to magnetic fields
- No vacuum, no HV, lightweight,...

The "zoo" of LLL sensors





For a world of choices in image sensors, come to





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The 17m Ø MAGIC IACT project for VHE γ astrophysics at E~ 25 GeV - 30 TeV



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Photograph of the 576-pixel imaging camera of MAGIC-I. In the central part one can see the 396 high resolution pixels of 0.10° size. Those are surrounded by 180 pixels of 0.20° .



VERITAS camera



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Outlook : the next 5-7 years Next generation VHE γ ray Observatory: CTA

MAGIC Phase II (MAGIC-I + MAGIC-II) in 2010 ~100 sources are already discovered



~500 scientists ~50 institutions



HESS Phase II (HESS + 28m Telescope) in 2012 ?



Astronomers in EU

JAPAN, US

^trzoyan: SiPMs for SST meeting, Live Cherenkov Telescope Array 1000's of sources will be discovered



Instrumental/technological improvements

Running target: light sensor improvements. Successfully pushing the PDE higher up. Shown for several types of PMTs



 Some 6 years ago we have launched a QE improvement program with manufacturers Hamamatsu (Japan), Photonis (France) and **Electron Tubes** Enterprises (England). The results were very encouraging Since about 1.5 years a new program has been launched for CTA; the results are shown on the left

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K8019MOD-100 DC Sensitivity and Data List for Trial Tubes												
Date: Jul.14.2010												
Serial	SK	SKb	SP	Q.E. (%)			Operating C	ain = 5E+04				
Number	(uA/Lm)		(A/Lm)	300 nm	350 nm	400 nm	voltage (V)	AP/Noise(%)	Canadate			
XA7105	63.9	10.6	14.3	22.5	25.7	25.5	950	0.0149				
XA7106	67.7	10.8	38.7	24.4	27.1	26.1	851	0.0133				
XA7107	96.8	12.2	56.9	24.1	26.9	26.4	845	0.0152				
XA7108	80.9	11.6	67.1	25.6	28.8	27.1	807	0.0172				
XA7110	128	14.8	71	33.3	36.4	35.2	861	0.0194	1			
XA7111	77.2	11.7	47.9	24.9	28.1	27.5	827	0.0142				
XA7112	76.2	11.8	41.1	25.4	29.0	28.1	855	0.0138				
XA7113	71.9	10.5	34.4	24.9	28.0	27.2	846	0.0191				
XA7114	66.6	10.7	33.5	22.5	25.6	25.0	862	0.0223				
XA7115	85.2	12.7	53.2	28.2	32.1	31.8	821	0.0189	2			
XA7116	133	14.6	72.1	32.3	34.9	33.1	876	0.0302				
XA7118	99.3	13	16.5	28.2	31.2	29.8	1005	0.0161	3			
XA7119	123	14.6	54.5	33.5	36.5	34.9	896	0.0266	4			
XA7120	125	14.4	49.7	31.2	33.4	31.7	882	0.0182	5			
XA7121	124	14.5	59.1	31.8	34.4	32.6	863	0.0258	6			
XA7122	124	14.9	43	33.8	34.1	33.0	917	0.0304				
XA7123	129	14.9	43.6	30.5	34.4	34.0	926	0.0511				
XA7124	132	15.1	33.3	31.9	35.9	35.1	954	0.0342				
XA7125	101	14.3	13.8	32.0	34.8	33.3	1027	0.0119	7			
XA7126	111	14.9	47.7	33.6	37.6	36.9	884	0.0152	8			
XA7127	90.1	12.9	33.2	29.1	32.8	32.6	892	0.0146	9			
XA7128	73.6	11.7	18.8	26.4	29.9	29.3	922	0.0282				
XA7129	80.7	12.1	19.5	26.8	30.4	29.8	930	0.0186	10			
XA7130	99.1	14.1	21.1	31.8	35.9	35.2	964	0.0135	11			
XA7131	101	14	26.7	32.6	36.2	35.1	951	0.0137	12			
XA7132	99.6	13.9	12.6	32.5	35.5	34.2	1034	0.0139	13			
XA7133	103	14.5	22.1	34.4	38.4	37.4	960	0.0152	14			
Ave-1	98.6	13.2	38.7	29.2	32.4	31.4	904	0.0202				
Ave-2	110.4	14.1	38.5	31.5	34.7	33.6	925	0.0215				

Ave-1: Average of all tubes Ave-2: Average of tubes with light blue color

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HAMAMATSU PHOTONICS K.K. Electron Tube Division

The most recent production of PMTs by Hamamatsu Photonics

Already now they came very close to requested parameters

The <QE> peak is approaching ~ 35 %. The ph.e. collection efficiency is 95-98 %.

Requested afterpulsing < 0.02 %.

More improvements requested, like much lower variation in the gain of dynodes

Currently launching a 2-year development contracts with Hamamatsu and ETE (England) Financial support from CTA

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ILC: Potential Consumer of (5-200)x10⁶ SiPMs

→Scintillation Calorimetry- for instance a SciTile Imagine Hadron Calorimeter for ILC (CALICE Collaboration),sci tile size:a few cm

→Typical threshold is ~ 5-7 phe



SiPM tile fibre system

- SiPM developed by MEPhI/PUSAR
 - Gain ~10°, bias ~ 50 V, size 1 mm², 1156 pixels
 - Eff (green) ~ 15%, quenching R ~ 1 10 MΩ
- SiPM tile fibre system integration: ITEP
 - 3x3x0.5 cm³ tiles from UNIPLAST, Russia
 - WLS fibre Kuraray Y11(300) 1mm
 - Matted edges, 2% light xtalk per edge
 - Faces covered with EM mirror foil







CAL CO

MSFDs for calorimetry



A big 8000 channel HCAL prototype with tail catcher is constructed by CALICE (DESY,ITEP,LAL,MEPHI,NIU,Prague,UK) for analogue and semidigital modes







B.Dolgoshein,SiPM review



One plane with SiPMs and WLS fibers installed into 3x3, 6x6 and 12x12 cm² 0.5 cm thick tiles

CERN test beam,2006

20

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SiPM: novel light sensors



Dolgoshein device

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SiPMs: MEPhI-MPI development: 1x1, 1.3x1.3, 1.4x1.4, 3x3, 5x5 mm²



- 5 x 5 mm²

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FACT = First G-APD Cherenkov Telescope for TeV Gamma Astronomy

TU Dortmund, EPF Lausanne, U Würzburg, ETH Zürich

Goal:

- Crab-observations in the coming period
- Test the technology (CTA, AGIS, MAGIC, ...)
- Will be operated for the DWARFprojects physics program !

Ready availability

- HEGRA-3 Telescope-Mount (La Palma):
- 8.5 m² mirror of good reflectivity
- Microcontroller-based Drive system
- Experience with 36 Pixel-Test camera M0







Why the light emission from Si avalanches is so important

- First observation of the light emission from reversed-biased Si p-n junction in 1955 (Newman)
- Revived interest about the effect in recent years because of:
- Cross-talk in SiPMs (GAPD, MPPC, micro-channel APD,...) spoils the amplitude resolution
- The light emission is proportional to the number of e- in the avalanche. This puts a limit to the maximum gain under which one can operate the SiPMs
- If no measures are taken against the cross-talk, then the Ffactor is worse than in classical PMTs
- As a consequence one encounters major problems in selftrigger schemes when measuring very low light level signals



When an avalanche is triggered in one SPAD we have:

- Secondary photons emission due to the avalanche current
- Photons propagation throughout the chip
- Secondary photon detection by a nearby detector



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Light Emission in Si Avalanches: collection of different measurements



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Our own measurements: the setup

- Components used in our setup:
 - (SiPM) MPPC S0362-11-100U from Hamamatsu
 - Imaging Single ph.e. Sensitive Spectrograph Shamrock 303i from Andor
 - CCD-camera *Idus 420 OE* for optical spectrum 450-1000nm
 - InGaAs –camera DU490 A-1.7 from Andor for NIR spectrum 900-1700nm

Sketch of our experimental setup



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The Absolute Calibration

- It was assumed that the used MPPC had an active depth of 1.8 µm.
- The emitted light absorption in Si was simulated by using a simple Monte Carlo with a step size of 0.1 µm in depth.
- Tabulated values of the light absorption in Si were used.
- Light reflection on the interface Si-SiO₂-air taken into account.
- One-by-one LEDs were inserted in the place of the MPPC
- A calibrated PIN photo diode was inserted just behind the gap of the spectograph. The CCD calibration by the manufacturer was used.

VIS LED,	470	520	621	700	750	810	910	1020
nm								
NIR LED, nm	910	1020	1200	1300	1450	1550	1600	1700

The used for calibration LEDs

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Reminder: light absorption in Si



• The related to absorption effects in Si were taken into account in our measurements

• Already from this graph one can get an impression about the relevant for the cross-talk effect wavelength range (>700 nm)

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Measured differential emission spectrum



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Possible emission mechanisms

Akil et al., 1999, Villa et al., 1995, Bude et al., 1992, ...

- Interband transitions between hot e- and holes
- Direct intraband e- transitions, Bremsstrahlung radiation from hot e- scattered by charged coulombic centers, and phonon-assisted e- transitions
- Ionization and indirect interband recombination of e- and holes under high-field conditions
- Intraband transitions of hot holes between the light and heavy-mass valence bands

Current status of SiPM and the prospects

- Currently there is a lot of enthusiasm about the new devices but the deep understanding is not simple, it comes only slowly
- One of the main problems of SiPMs is the low PDE, that is not easy to measure. It shall be disentangled from the cross-talk and afterpulsing.
- The afterpulsing in PMTs is a ~1% effect on single ph.e. level, while for example, for currently existing MPPC's from Hamamatsu it is a 20-30 % effect. This shall strongly manifest itself in self-trigger mode
- Usually the real value of PDE is much lower than the claimed (advertised) one. The reason is the low applied overvoltage.
- For ~100 % Geiger efficiency and a high PDE one needs to apply an overvoltage that is 15-20 % higher than the breakdown one. The commercially available devices cannot do this yet (because of their design they do not quench above an applied overvoltage of 2.5 %).
- Already during this year some type of SiPMs with good UV response and a low cross-talk level could become available.
- Hamamatsu, Philips, Perkin-Elmer and some other companies are working on it.

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→ Long tail in SiPM pulse hight distribution vs threshold



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Optical Crosstalk OC

P. Buzhan, B. Dolgoshein, et al., 2009

OC has two components

FIRST:phe's are induced in high electric field depletion region of neibouring pixels

→this mechanism is very fast: ~1ns(prompt OC)

SECOND : The same in undepleted region and then the diffusion(or drift) to high electric field Geiger region of neibouring pixels

 \rightarrow this process is delayed: later than 1ns



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A filled in trench



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First step: SiPM 1.4x1.4 mm2 with OC suppression topology



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Timing by SiPM: possible application for Cherenkov Imaging Counters



SiPM:

• position sensitive (~1 mm²)

 a single photon detection capability with background hits density : 2.10⁻³ 1/ns·mm² (room temperature) 3.10⁻⁴ 1/ns·mm² (-50°C) insensitive to magnetic field
good time resolution (~50 ns rms)

FWHM: Laser (40 ps) + electronics (60 ps) => SiPM (100 ps)

Pulse width depends on the SiPM chip size





A single ph.e. pulse shape for different SiPMs

All tested devices had µ-cell size of 100µm x 100µm

Operated under gain: 10⁷



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SiPM time resolution



Second step: 5x5mm2 SiPM with OC and AP suppression

SiPM parameters:

🗲 size

5x5mm2

- → double junction structure with optical barriers 6mkm
- \rightarrow number of pixels
- → pixel size
- → gain
- → geometrical eff.(filling factor)
- → pixel capacitance
- → output SiPM capacitance
- → antireflection entrance window
- → single pixel recovery time

1600 100mkm 2×10*7 64% ~1pF ~160pF

~ .5mks





Figure 3: $25(5 \times 5)mm^2$ SiPM. It consists of the array of $1600(40 \times 40)$ micropixels with $100 \times 100 \mu m^2$ size.

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Timing by 5x5mm2 SiPM: signal shape

- Because high SiPM output capacitance (~160pF)
 - a special FE electronics has been developed: low imput impedance(a few Ohm) current amplifier+shaper



→ The lifetimes of trapped electron are mostly rather small: less than ~100 ns



Therefore a single pixel recovery time Rquench x Cpixel sould not be not very small and recommended at level of .5-1 mks →Even for high Gain x PDE the Afterpusing has to be small enough: AP(Gain=10*7)=~1% for recovery time of >500ns

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- → Give rise the non-Poisson statistics of fired pixels (SiPM response).
- \rightarrow As a result:

→ SiPM pulse hight resolution is worsening: →(sigma/A)*2 > 1/N phe Excess Noise Factor ENF >1 →Sci Spectrometry(PET etc.)?

ENF: for PMT ~ 1.2 for APD ~ 2-2.5 for SiPM(desirable) < 1.05



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The cross-talk effect (optical coupling: OC) has a major impact in self-trigger schemes, it can prohibit obtaining a low threshold setting



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Optical Crosstalk studies



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SiPM with cross-talk suppression: World record of ultra-fast light sensors in amplitude resolution



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• A curious experiment: what will happens if one will hold a mirror in front of a SiPM ?

• The emiited light bounces back strongly amplifying the cross-talk effect

 Similarly the amplitude resolution shall degrade when SiPMs are coupled to scintillators (Dolgoshein et al., under preparation)

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High optical cross-talk and afterpulsing: that's why the advertised by Hamamatsu PDE for MPPCs (red) differ from measured ones (green)



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A PDE and gain of a 1x1 mm² SiPM produced by PEI measured at +20°C

Overvoltage = operational voltage – breakdown voltage



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Prompt OC suppression using Si damaged by ion implantation



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Dark count rate: SiPM 1x1mm^2, OC=4%,AP=1% room temperature

SiPM 1x1 mm² P on N , (pixel size size 100x100 µm) with OC and AP suppression



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Digital SiPM

→single pixel dark
 count rate is lower by
 factor of 1.5-2
 (~physical limit)
 →digital output is
 more convenient for
 system integration

→PDE loss (filling factor is less due to electronics on chip)
 →problems with
 Optical Crosstalk and Afterpulsing have to be solved

Fabrication cost?

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PHILIPS

Digital Photon Counting – The Concept

Intrinsically, the SiPM is a digital device: a single cell breaks down or not



Philips Digital Photon Counting, October 27th, 2009

R. Mirzoyan: SiPMs for CTA SST, SST meeting, Liverpool

www.philips.com/digitalphotoncounting

PDE ,SiPM p on n,3x3 mm², OV/V=12% +OC suppression

Test-product of PEI, to become soon commercial product

SiPM 3x3 mm² P on N (pixel size 100x100 μ m, geom. eff. = 0,6) T = -50 $^{\circ}$ C



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Conclusions

- In a time scale 1-2 years from now one can buy SiPMs with outstanding characteristics, probably from several manufacturers.
- Their sizes could span 1-10 mm.
- SiPM cost will be reduced due to the availability of full CMOS designs. Several USD per mm² is not unrealistic.
- They could offer PDE of 60-65 %, x-talk < 1% and low temperature and voltage dependences.
- These devices are going to substitute classical PMTs and APD in many applications, including those in physics instrumentation in, for example, nuclear medicine (timeof-flight PET,...).
- Realistic candidates for SST telescopes, especially for 2optical element designs

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